

**Amendments to the Claims:**

This listing of claims will replace all prior versions, and listings, of claims in the application.

**Listing of Claims:**

1. (Previously Presented) A method of manufacturing a plasma display panel, the method comprising the steps of:

providing a substrate holder above a source of deposition material, the substrate holder including:

a plurality of first frames for holding a plurality of substrates for a respective plurality of plasma display panels, said plurality of first frames have a protrusion between them which extends from below a bottom surface of the substrate along a side surface of the substrate to a height above the substrate and greater than a height of the substrate without being superimposed over the top surface of the substrate; and

a plurality of second frames each having a respective opening, protrusions situated between each of the second frames and the plurality of first frames so that the substrates are on one side of each of the protrusions and each respective opening is on another side of each of the protrusions, the protrusions also extending above the substrates without being superimposed over the tops of the substrates, and an unobstructed path exists from said source of deposition material to a top surface of said substrate;

providing the plasma display panel which is held by the substrate holder for deposition;

spraying said deposition material onto said bottom surface of said substrate from below the substrate;

and permitting an additional amount of said deposition material to flow through said opening from below the substrate.

2. (Currently Amended) The method of manufacturing a plasma display panel as defined in Claim 1, wherein ~~a height~~heights of the protrusion ~~is~~and the protrusions are between 1 mm and 100 mm.

3. (Currently Amended) The method of manufacturing a plasma display panel as defined in Claim 1, the first frame comprising holding means including support means for supporting the ~~substrate~~plurality of substrates from underneath and positioning means for positioning the ~~substrate~~plurality of substrates in a planar direction, wherein the ~~substrate~~plurality of substrates are held by fitting the ~~substrate~~plurality of substrates to the positioning means and placing the ~~substrate~~plurality of substrates on the support means.

4. (Previously Presented) A substrate holder system for a plasma display panel, the substrate holder system comprising:

a plurality of first frames for holding a plurality of substrates for a respective plurality of plasma display panels, said plurality of first frames being provided with a protrusion between them which extends from below a bottom surface of the substrate along a side surface of the substrate to a height above the substrate greater than a height of the substrate without being superimposed over the top surface of the substrate,

a plurality of second frames each having a respective opening, protrusions situated between each of the second frames and the plurality of first frames so that the substrates are on one side of each of the protrusions and each respective opening is on another side of each of the protrusions, the protrusions also extending above the substrates without being superimposed over the tops of the substrates;

and a source of deposition material below said substrate which sprays said deposition material towards the bottom surface of the substrate and through the opening;

wherein an unobstructed path exists from said source of deposition material to a top surface of said substrate.

5. (Currently Amended) The substrate holder system for a plasma display panel as defined in Claim 4, wherein ~~a height~~heights of the protrusion ~~is~~and the protrusions are between 1 mm and 100 mm.

6. (Currently Amended) The substrate holder system for a plasma display panel as defined in Claim 4, the first frame comprising holding means including support means for supporting the ~~substrate~~plurality of substrates from underneath and positioning means for positioning the ~~substrate~~plurality of substrates in a planar direction, wherein the ~~substrate~~plurality of substrates are held by fitting the ~~substrate~~plurality of substrates to the positioning means and placing the ~~substrate~~plurality of substrates on the support means.

7. (Currently Amended) The substrate holder system for a plasma display panel as defined in Claim 4, wherein the first frame includes a plurality of supports separated from each other which extend below the bottom surface of the ~~substrate~~plurality of substrates.

8. (Currently Amended) The substrate holder system for a plasma display panel as defined in Claim 4, said second frame maintained with said opening while ~~said substrate is~~the plurality of substrates are situated in said first frame.

9. (Currently Amended) A method of manufacturing a plasma display panel as defined in Claim 1, wherein the ~~protrusion curves~~protrusions curve away from the ~~substrate~~plurality of substrates.